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## CLAIMS

1. A substrate transfer apparatus for a component  
5 mounting machine, for transferring a substrate into a  
mounting process (8) in which components are mounted onto  
the substrate and transferring the substrate from said  
mounting process (8), comprising:

a mounting-waiting process (7) for making the  
10 substrate to be transferred into the mounting process (8)  
wait before the mounting process (8); and

a substrate discharge-waiting process (9) for making  
the substrate after being transferred from the mounting  
process (8) wait before a following process, wherein:

15 transfer of an unmounted substrate (3) from said  
mounting-waiting process (7) to the mounting process (8)  
and transfer of a mounted substrate (2) for which mounting  
has been done in the mounting process (8) from the mounting  
process (8) to the substrate discharge-waiting process (9)  
20 are performed simultaneously,

characterized in that detecting means (6) are provided  
for detecting that a plurality of substrates have been  
transferred into the substrate discharge-waiting process  
(9) as part of the same transfer.

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2. The substrate transfer apparatus for a components  
mounting machine according to claim 1, wherein the  
detecting means includes: a substrate-arrival detecting  
sensor (5c) for detecting the mounted substrate (2)  
30 transferred into the substrate discharge-waiting process  
(9); and a substrate-continuity detecting sensor (6),  
provided upstream of the substrate-arrival detecting sensor  
(5c), for detecting an unmounted substrate (3) being  
transferred at the same time as a mounted substrate (2).

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3. The substrate transfer apparatus for a component  
mounting machine according to claim 2, wherein the

substrate-continuity detecting sensor (6) is arranged at a position that satisfies  $X < X_S < 2X$ , where a distance from the substrate-arrival detecting sensor (5c) to the substrate-continuity detecting sensor (6) is  $X_S$  and a  
5 substrate dimension in the substrate transfer direction is  $X$ .

4. The substrate transfer apparatus for a component mounting machine according to claim 3, wherein the  
10 substrate-continuity detecting sensor (6) is arranged to be movable to the position that satisfies  $X < X_S < 2X$ .

5. The substrate transfer apparatus for a component mounting machine according to claim 3, wherein the  
15 substrate-continuity detecting sensor (6) is constructed to be automatically movable to the position that satisfies  $X < X_S < 2X$ , in accordance with the substrate dimension  $X$  in the substrate transfer direction.

20 6. The substrate transfer apparatus for a component mounting machine according to claim 1, wherein the detecting means includes: a substrate-arrival detecting sensor (5c) for detecting the mounted substrate (2) transferred into the substrate discharge-waiting process  
25 (9); and a plurality of substrate-continuity detecting sensors (6a, 6b, 6c), provided upstream of the substrate-arrival detecting sensor (5c) at different positions in a substrate transfer direction from one another, for detecting an unmounted substrate (3) being transferred at  
30 the same time as the mounted substrate (2).

7. The substrate transfer apparatus for a component mounting machine according to claim 6, wherein the  
35 substrate-continuity detecting sensors (6a, 6b, 6c) detect an unmounted substrate (3) by a substrate-detection state of one (6b) of the plurality of substrate-continuity detecting sensors (6a, 6b, 6c) that is located at a

position satisfying  $X < X_S < 2X$ , where a distance from the substrate-arrival detecting sensor (5c) to the one substrate-continuity detecting sensor (6b) is  $X_S$  and a substrate dimension in the substrate transfer direction is  $X$ .

8. The substrate transfer apparatus for a component mounting machine according to any one of claims 6 and 7, wherein the substrate transfer apparatus includes a minimum required number of the substrate-continuity detecting sensors (6a, 6b, 6c) by arranging  $N$  sensors that satisfy  $2^n \times P_{\min} > P_{\max}$  at positions determined by  $2^n \times P_{\min} 2$  ( $n = 1, 2, \dots, N$ ) from a minimum substrate size ( $P_{\min}$ ) and a maximum substrate size ( $P_{\max}$ ) in the substrate transfer direction, respectively, for which the electronic component mounting machine (1) is intended.